

AND TRADEMARK OFFICE

In re Patent Application of

S. Y. LI et al.

Application No.: 09/820,695

Filed: March 30, 2001

METHOD OF PLASMA ETCHING

LOW-K DIELECTRIC MATERIALS

MAIL STOP AF

Group Art Unit: 1763

Examiner: A. W. Olsen

Confirmation No.: 4162

AMENDMENT



Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

In response to the Office Action mailed June 6, 2005, please amend the above-identified patent application as follows: